Chao Han

List of Publications by Year
in descending order

28	204	1040056 9	1058476 14
papers	citations	h-index	g-index

28	28	28	145
all docs	docs citations	times ranked	citing authors

#	Article	IF	Citations
1	Realization of a micro pressure sensor with high sensitivity and overload by introducing beams and Islands. Microsystem Technologies, 2015, 21, 739-747.	2.0	35
2	Design and fabrication of a resonant pressure sensor by combination of DETF quartz resonator and silicon diaphragm. Microsystem Technologies, 2015, 21, 631-640.	2.0	21
3	A Differential Resonant Accelerometer with Low Cross-Interference and Temperature Drift. Sensors, 2017, 17, 178.	3.8	19
4	A resonant sensor composed of quartz double ended tuning fork and silicon substrate for digital acceleration measurement. Review of Scientific Instruments, 2014, 85, 035004.	1.3	18
5	A Quartz Resonant Ultra-High Pressure Sensor With High Precision and High Stability. IEEE Sensors Journal, 2021, 21, 22553-22561.	4.7	15
6	High-Stability Quartz Resonant Accelerometer With Micro-Leverages. Journal of Microelectromechanical Systems, 2021, 30, 184-192.	2.5	11
7	An integrated packaged resonant accelerometer with temperature compensation. Review of Scientific Instruments, 2020, 91, 105004.	1.3	10
8	Geometry optimization for micro-pressure sensor considering dynamic interference. Review of Scientific Instruments, 2014, 85, 095002.	1.3	9
9	A micro-machined differential resonance accelerometer based on silicon on quartz method. Sensors and Actuators A: Physical, 2017, 253, 1-9.	4.1	9
10	A high sensitivity quartz resonant pressure sensor with differential output and self-correction. Review of Scientific Instruments, 2019, 90, 065003.	1.3	8
11	Modelling and characterisation of a micromachined resonant pressure sensor with piezoelectric excitation and sensing. Micro and Nano Letters, 2016, 11, 326-331.	1.3	6
12	Development of V-Shaped Beam on the Shock Resistance and Driving Frequency of Micro Quartz Tuning Forks Resonant Gyroscope. Micromachines, 2020, 11, 1012.	2.9	5
13	Deep Reactive Ion Etching of Z-Cut Alpha Quartz for MEMS Resonant Devices Fabrication. Micromachines, 2020, 11, 724.	2.9	5
14	The quality factor of quartz DETF for resonant sensors: simulation, analysis and verification. Journal of Micromechanics and Microengineering, 2021, 31, 115001.	2.6	5
15	Feasibility study of a pressure sensor based on double-ended tuning fork quartz resonator. , 2014, , .		4
16	Configuration improvement for micropressure sensor with vibration interference. Micro and Nano Letters, 2014, 9, 680-685.	1.3	4
17	Microresonant accelerometer composed of silicon substrate and quartz doubleâ€ended tuning fork with temperature isolator. Micro and Nano Letters, 2014, 9, 664-668.	1.3	4
18	Research on a Micro-Processing Technology for Fabricating Complex Structures in Single-Crystal Quartz. Micromachines, 2020, 11, 337.	2.9	4

#	Article	IF	Citations
19	A micro resonant acceleration sensor comprising silicon support with temperature isolator and quartz doubled ended tuning fork. , 2014, , .		2
20	Research on slide-film damping effect to achieve a high-performance resonant pressure senor. , 2015, , .		2
21	Optical microâ€electroâ€mechanicalâ€system pressure sensor based on light intensity modulation. Micro and Nano Letters, 2015, 10, 491-495.	1.3	2
22	A Novel Resonant Accelerometer Based on Quartz on Silicon (QoS). , 2019, , .		2
23	Research on micro-leverage in monolithic quartz resonant accelerometer. Review of Scientific Instruments, 2021, 92, 025005.	1.3	2
24	A micro-pressure sensor with high sensitivity and overload resistance. , 2013, , .		1
25	Achievement of a high-sensitive and high-overload sensor based on the bossed-diaphragm structure. , 2014, , .		1
26	Design and analysis of a micro pressure sensor with optical fiber. , 2015, , .		0
27	Design of a resonant accelerometer integrated with a diamond like carbon film temperature sensor. , 2017, , .		0
28	Analysis and Simulation of the Influence of â€œVâ€•Beam on the Impact Resistance of Micro Quartz Tuning Gyroscopes. , 2019, , .		0